

Trento, lì 16 luglio 2018

**Oggetto:** nomina della Commissione tecnica nella procedura aperta per la fornitura di attrezzature scientifiche per il potenziamento della micro nano facility della Fondazione Bruno Kessler verso la nanofabbricazione d'avanguardia. **CUP C67F18000000001**

### IL PRESIDENTE

- **PREMESSO che** con Determinazione a contrarre Prot. n. 09/reg. det. di data 24 maggio 2018 per l'appalto di fornitura di attrezzature scientifiche per il potenziamento della micro nano facility della Fondazione Bruno Kessler verso la nanofabbricazione d'avanguardia si è dato avvio alla procedura aperta con bando GUCE 2018/S 102-232601 di data 31/05/2018 con applicazione del criterio dell'offerta economicamente più vantaggiosa individuata sulla base del miglior rapporto qualità/prezzo, ai sensi degli artt. dell'art. 60 e 95 del D.Lgs. 18 aprile 2016, n. 50 e degli art. 16 e 17 della L.P. 9 marzo 2016 n. 2;
- **PRESO ATTO che** la procedura di affidamento in oggetto è divisa in cinque lotti: Lotto 1 - PLASMA ETCHING CIG 7501842BD9; Lotto 2 - FIB-SEM CIG 7501935899; Lotto 3 - ICP-PECVD CIG 750202962C; Lotto 4 - SISTEMA MULTITARGET CIG 7502070801 e Lotto 5 - PROBER AUTOMATICO CIG 7502096D74;
- **CONSIDERATO che** l'art. 77 del D.Lvo 50/2016 prevede che per i settori ordinari, quando il criterio di aggiudicazione è quello dell'offerta economicamente più vantaggiosa, la valutazione delle offerte dal punto di vista tecnico ed economico è affidata ad una commissione giudicatrice;
- **ATTESO che** allo stato attuale non risulta ancora operativo l'Albo dei commissari di gara istituito e gestito da ANAC di cui all'art. 78 del D.Lvo 50/2018 dal quale selezionare i membri della commissione per la valutazione delle offerte nelle gara di importo superiore alla soglia comunitaria e che, pertanto, trova ancora applicazione l'art. 216, co. 12, del medesimo D.Lvo secondo il quale "Fino alla adozione della disciplina in materia di iscrizione all'Albo di cui all'articolo 78, la commissione giudicatrice continua ad essere nominata dall'organo della stazione appaltante competente ad effettuare la scelta del soggetto affidatario del contratto, secondo regole di competenza e trasparenza preventivamente individuate da ciascuna stazione appaltante";
- **CONSIDERATO che** il termine per la presentazione delle offerte è scaduto in data 11 luglio 2018 alle ore 16.00 e che, pertanto, è possibile procedere alla nomina dei commissari e alla costituzione della commissione;
- **PRESO ATTO che** gli operatori economici partecipanti alla gara sono i seguenti:

LOTTO 1	CIG 7501842BD9	PLASMA ETCHING	Thin Film Equipment srl C.F. 03189010964 Gambetti Kenologia srl P.I. 08000120157
LOTTO 2	CIG 7501935899	FIB-SEM	RAITH GmbH P.I. DE124727617

LOTTO 3	CIG 750202962C	ICP-PECVD	Gambetti Kenologia srl P.I. 08000120157 Elettrorava spa P.I. 00472890011
LOTTO 4	CIG 7502070801	SISTEMA MULTITARGET	FHR Anlagenbau GmbH P.I. DE140206677 Kenosistec srl P.I. 02837890546 Polytechnik AS P.I. DK26672031
LOTTO 5	CIG 7502096D74	PROBER AUTOMATICO	Accretech Europe GmbH DE151305933

- **PRESO ATTO** che la commissione deve essere composta da un numero dispari di componenti, in numero massimo di cinque, esperti nello specifico settore cui si riferisce l'oggetto del contratto (articolo 77, comma 2, del D.Lgs. 18 aprile 2016, n. 50);
- **RITENUTO** di selezionare i commissari tra il personale interno della Fondazione e quindi di nominare quali componenti della commissione i dipendenti di seguito indicati, muniti di qualificazione, funzioni e ruoli che ben giustificano la partecipazione alla Commissione stessa:
  - Massimo Bersani - Program Manager e Senior Researcher CMM,
  - Benno Margesin - Senior Researcher CMM;
  - Maurizio Boscardin - Senior Researcher CMM;
- **CONSIDERATO che**, qualora taluno dei suddetti componenti della commissione tecnica sia impossibilitato a presenziare alla stessa, il Presidente della Commissione provvederà a surrogarlo all'apertura della seduta disponendo menzione in calce al verbale di gara;
- **RITENUTO** di dover allegare al presente atto i *curricula* dei componenti la Commissione per la pubblicazione del presente atto nella sezione "Amministrazione trasparente", ai sensi dell'art. 29 comma 1 del D.Lgs. 18 aprile 2016, n. 50 e con l'applicazione delle disposizioni di cui al D.Lgs. 14 marzo 2013, n. 33;
- **STABILITO che**, per l'espletamento dell'incarico, non è previsto alcun compenso aggiuntivo per i componenti della suddetta Commissione;

#### **DETERMINA**

1. che la premessa forma parte integrante e sostanziale del presente provvedimento;
2. di nominare la Commissione di gara per l'affidamento del servizio di elaborazione delle retribuzioni, consulenza adempimenti correlati per i dipendenti e collaboratori della Fondazione Bruno Kessler secondo quanto definito nei documenti di gara, nelle persone di:
  - **Massimo Bersani: Presidente**
  - **Benno Margesin: Componente**
  - **Maurizio Boscardin: Componente**
3. di demandare alla Commissione lo svolgimento di tutte le operazioni valutazione delle offerte tecniche;
4. di dare atto che, per l'espletamento dell'incarico, non è previsto alcun compenso aggiuntivo per i componenti della suddetta Commissione;
5. di disporre la pubblicazione del presente atto e dei *curricula* dei componenti la

Prot. n. 12/reg. det.  
d.d. 16 luglio 2018

Commissione nella sezione "Amministrazione trasparente" del sito della Fondazione in adempimento all'art. 29 del vigente Codice dei Contratti.

Il Presidente  
Prof. Francesco Profumo  
(f.to in originale)



## Europass Curriculum Vitae

### Personal information

First name(s) / Surname(s)	<b>Massimo Bersani</b>
Address(es)	Fondazione Bruno Kessler, Via Sommarive 18, 38123 Povo (Tn), Italy
Telephone(s)	Mobile:
Fax(es)	
E-mail	bersani@fbk.eu
Nationality	Italian
Date of birth	
Gender	Male

### Work experience

Dates	1/1/2017-present: Researcher Senior at FBK Program Manager at CMM (Centre of Materials and Microsystems; ; <a href="http://cmmf.fbk.eu/">http://cmmf.fbk.eu/</a> ) 10/8/2017-18/10/2017 Visiting Professor at Unochapecò, Santa Caterina Brasil 1/3/2014-1/1/2017: Researcher Senior at FBK, strategic marketing responsible for MNF (Micro and Nano Facility; <a href="http://mnf.fbk.eu/">http://mnf.fbk.eu/</a> ) 2014-present Advisory board member of the FIM department at University of Modena 2015-2016: Attend the Executive Master in Business and Administration of Luiss Guido Carli University in Rome. 20/6/2014-20/9/2014 Visiting Professor at University of Maryland USA 2008-2014: Researcher Senior at FBK (Fondazione Bruno Kessler; <a href="http://www.fbk.eu/">www.fbk.eu/</a> ); MiNALab (Mico Nano Analytical Laboratory; <a href="http://minalab.fbk.eu/">http://minalab.fbk.eu/</a> ) research unit responsible 2003-2008: Researcher R2 level at ITC-irst, MAME line (Materials and Analysis for Microelectronics) responsible Physical and Chemical Surfaces and Interfaces Division 1997-2003 Research scientist of the Physical and Chemical Surfaces and Interfaces Division at ITC-irst 1994-1997 Postdoctoral fellow SGS-Thomson Microelectronics at CMBM (Materials Center and Medical Biophysics) Advanced Material Division, Povo-Trento (Italy) 1993-1994 Grant at Physics Department of Modena University, Italy.
Present position held	Researcher Senior at FBK, Program Manager of the Centre of Materials and Microsystems, working in the direction staff.

Main activities and responsibilities	<p>Support to management activities of the CMM</p> <p>Management of the industrial and institutional partnerships;</p> <p>Member of management board of the CMM</p> <p>Valuable activity in projects writing</p> <p>Definition and implementation of CMM marketing plan</p> <p>Direct involvement in financed projects</p> <p>Past Activities and responsibilities</p> <p>January 2008 – January 2011 ATHENIS – FP7 STREP (about 2.000.000 euro funding) FBK responsible</p> <p>December 2006 – March 2011: EU ANNA FP6 I3 (about 6.000.000 euro funding), Coordinator</p> <p>December 2002 – November 2004: EU Impulse FP 5 (about 2.300.00 euro funding), ITC-irst responsible</p> <p>September 2000 - October 2002: EU-ILSIMS FP5 (about 1.000.000 euro funding), ITC-irst responsible</p> <p>Responsible of several regional financed projects</p> <p>Responsible of more than 20 contracts with industries for a total funding over 1.000.000 euro</p>
Name and address of employer	Fondazione Bruno Kessler Via S. Croce, 77 I-38122 TRENTO
Type of business or sector	Research
<b>Education and training</b>	
Dates	December 1993
Title of qualification awarded	Doctor in Physic
Name and type of organisation providing education and training	University of Modena
Dates	May 2015 Devenber 2016
Title of qualification awarded	Executive Mater in Businnes Administation
Name and type of organisation providing education and training	University Luiss Guido Carli Rome
<b>Teaching Experiences</b>	<p>2017 Teacher of the 45-hour course: Nanoscience and Nanotechnology overview at the University of Capeco state of Sata Caterina Brazil <a href="https://www.unochapeco.edu.br/">https://www.unochapeco.edu.br/</a></p> <p>2017 Teacher of the 24-hour course: Innovation Managment; at the university of Capeco state of Sata Caterina Brazil <a href="https://www.unochapeco.edu.br/">https://www.unochapeco.edu.br/</a></p> <p>2017 Teacher of the 8-hour course: Project Plannng and Elaboration: at the university of Capeco state of Sata Caterina Brazil <a href="https://www.unochapeco.edu.br/">https://www.unochapeco.edu.br/</a></p> <p>2017 Teacher of the 20-hour course: Entrepreneurship with innovation; at the university of Capeco state of Sata Caterina Brazil <a href="https://www.unochapeco.edu.br/">https://www.unochapeco.edu.br/</a></p>

**Mentoring Experiences**

1. DfP technologies a company producing X-ray instrumentation; role business and innovation project consultant
2. Industrial projects consulatnt(including SME in H2020) Novurania
3. Start up Indivenire, role business consultant
4. Start up SMETRO; role business consultant

**Editor**

Pproceedings ANALYTICAL TECHNIQUES FOR SEMICONDUCTOR MATERIALS AND PROCESS CHARACTERIZATION 6. (ALTECH 2009) (216TH ECS MEETING) ECS Transactions Volume 25 No.03 ISBN: 9781607680901 Pages: 465 (1 Vol)  
 Guest editors of Surface and Interface analysis, January 2013, Volume 45, Issue 1, ISSN 0142-2421. Special issue SIMS XVIII

Mother tongue(s)

**Italian**

Other language(s)

**English, French, Portuguese**

Self-assessment

*European level (\*)***English****French****Portuguese**

Understanding		Speaking		Writing			
Listening		Reading		Spoken interaction		Spoken production	
	C2		C2		C2		C2
	A2		A2		A1		A1
	B1		B1		B1		A1

(\*) [Common European Framework of Reference for Languages](#)

Social skills and competences

Good communication skills

Organisational skills and competences

Evaluable and proved experience and competences in Business Administration. In particular: Corporate Marketing; People Management; Innovation Management; Communication

Technical skills and competences

Analytical methodology development for dopant distribution determination in semiconductor materials. The work is focused on ultra shallow junctions in order to determine dopant diffusion mechanisms and depth distribution.

Extraction of new knowledge from high dimensional mass spectrometry data through multivariate data analysis techniques to solve specific problems in the agricultural and food chemistry field

Application of surface analytical multi-techniques approach to fully characterize industrial coating for metal substrates. Support Industrial research and development by using industrial deposition equipment joint to state of art analytical approach

Physics and Materials Science in semiconductor technology. Experimental characterisation of semiconductors, interfaces, microelectronics materials.

Development of innovative X-ray diffraction instrumentation. Management of Prototype instruments realization.

Multitechnique analytical approaches on various surface science applications

Analytical industrial service

Computer skills and competences

Advanced computer skill in Microsoft suite

Other skills and competences

Replace this text by a description of these competences and indicate where they were acquired. (Remove if not relevant, see instructions)

Driving licence

B

**Additional information**

Number of papers on international peer reviewed journals: 140  
Number of papers at Int. congresses with review: 79  
H-index: 20  
Number of citations: about 1100  
Guest editors of a special number of Surface and Interface Analysis  
Total number invited lectures, seminars and tutorials: 30  
Total number of talks at conferences and workshops: 60

## PERSONAL INFORMATION

## Maurizio Boscardin

 [boscardi@fbk.eu](mailto:boscardi@fbk.eu)<http://mtlab.fbk.eu/people/profile/boscardi>

Sex Male | Date of birth | Nationality Italian

## WORK EXPERIENCE

From February 1988 to May 1989

## fellow at the Microsystems Division of ITC-IRST Trento

ITC-IRST Trento

- Micro fabrication process

From May 1989 to present

## Researcher at Microsystems Division of ITC-IRST Trento

ITC-IRST Trento

- Development of double sided microstrip detectors on high resistivity silicon for applications in HEP experiments as ALICE Cern, Babar Slac, AMS

From 2001 to 2008

## Manager of the "SRD Silicon Radiation Detector" project

ITC-IRST Trento

- Developments of radiations detectors with monolithic integration of pre amplifier based on Jfet technology for applications on ambient radiation monitoring
- Development of Silicon Photo Multiplier (SiPM);
- Development of PAD detectors used for i) clinic dosimeter in partnership with INFN Firenze and Ospedale Carrugi, ii) applications in Nuclear Physics experiment in partnership with INFN Legnaro

From 2008 to 2010

## Manager of Micro technology lab of MTLab FBK

CNM FBK Trento

- Coordination of the activity of the lab
- Developments of technology platform

From to 2010 to 2014

detectors for HEP and MEMS

## Manager of R&amp;D activity of MTLab

CNM FBK Trento

- Development of radiation detector based on a columnar structures ( Si -3D) for the Insertable B layer of ATLAS Cern experiment-.
- Development of Silicon Drift Detectors
- Micro-oscillator - based on MEMS devices - for quantum optical measurements
- C-Mut for ecografics applications
- 

Business or sector developments of micro fabrications process for silicon radiations detectors and detectors for HEP and MEMS

From to 2014 to present

## Senior Researcher at MNF

- Development of radiation detector based on a schottky diode on SiC.
- Development of Edgless Radiation Detectors for CERN (Atlas and CMS experiments)
- Development of a chip cooling based on DRIE technique
- Production of Silicon Microstrip for CSES satellite
- Development of Ultra Fast Silicon Detectors for timing application



- Development of bio inspired silicon surface ( control of wettability)
  - Development of silicon tools for the “chip cooling”
  -
- Business or sector** developments of micro fabrications process for silicon radiations detectors and detectors for HEP and MEMS

EDUCATION AND TRAINING

July 1986 degree in Physics, University of Trento, Italy

Replace with EQF (or other) level if relevant

PERSONAL SKILLS

Mother tongue(s) Italian

Other language(s)

	UNDERSTANDING		SPEAKING		WRITING
	Listening	Reading	Spoken interaction	Spoken production	
English	B1	B1	B1	B1	B2
Replace with name of language certificate. Enter level if known.					

Levels: A1/2: Basic user - B1/2: Independent user - C1/2 Proficient user  
Common European Framework of Reference for Languages

Organisational / managerial skills

Job-related skills ▪ mentoring skills

Computer skills ▪ good command of Microsoft Office™ tools

ADDITIONAL INFORMATION

- Publications Authors of over 280 articles published in scientific journals or presented at international conferences, as well as two European patents
- Presentations
- Projects
- Conferences
- Seminars
- Honours and awards
- Memberships
- References

ANNEXES

## **BENNO MARGESIN**

Date/place of birth

Gender            Male

### **SCIENTIFIC AND PROFESSIONAL CAREER**

Benno Margesin is senior researcher at FBK.

He graduated in physics in 1980 at the University of Bologna with a thesis on electron optics applied to the electron microscopy. In 1982 he joined the former “Istituto Trentino di Cultura” of Trento and started his research career as a researcher of the ion implantation group. Within the ion implantation group, he was involved in the design and development of heavy ion sources and of electron-optical elements for heavy ion implanters.

He joined in 1987 the Integrated Circuits Fabrication Laboratory, now the MicroNanoFabrication Facility of FBK. Since 1992 he is also involved in the development of sensors and the study of micromechanics. In particular he developed physical and chemical sensors and their fabrication processes, as there are cryogenic micro-calorimeter, ISFET's, LAPS, biosensors, pressure sensors, microelectrodes and passive components for microwave circuits, for applications in research and industry. From 2000 his activity became more specialized first on capacitive MEMS microphones and then on RF MEM switches, an activity that occupied most of his time in the last 15 years and was extended to include also techniques for wafer-level packaging.

In 1997 he became the leader of the “BioMEMS” group at ITC-irst.

Starting from 2001 his major involvement is in the development of a technology platform for RF switches that has been used to develop a large number of RF circuits and components within research projects funded by the European Commission, the European Space Agency and industrial partners.

His activity on RF MEMS devices dates back to the beginning of the INCO COPERNICUS Project No. 977131 “Micromachined circuits for microwave and millimeter wave applications - MEMSWAVE”, where he collaborated in the development of low loss passive RF components. Starting from 2001 his major involvement is in the development of a technology platform for RF switches, first within the ESA/ESTEC Contract Nr. 14628/NL/CK-MEM Switch as a subcontractor of Alcatel Alenia Space and then within the NoE AMICOM, where he has worked on the optimization and extension of the RF switch technology platform. Next he was involved in the development of a Very Large Switching Matrix and a High Reliability Redundancy Switch (both projects funded by ESA). He also contributed to two EU projects, one is the STREP ARARSCOM where he is involved in the development of reflectarrays and the other is MEMSPACK, which was dedicated to the development and assessment of the MEMS packaging concepts.

His activity on cryogenic microcalorimeters and bolometers dates back to 1992 when he got involved by Prof. E. Fiorini in the development of implanted Silicon bolometers to be used in experiments for the measurement of the neutrino mass.

In 1998 and the years after he developed and produced the calibration resistors for the CUORE experiment.

In 2007, following a suggestion from Prof. P. De Bernardis from the University La Sapienza in Rome, he started to work on Kinetic Inductance Detectors based on grounded coupled co-planar waveguides

coupled capacitively to a readout line build in different superconductors. In the following years he build different demonstrators for the detection of the CMB radiation detection.

In the last years he worked on the proximity effect in superconductors in order to develop multi layer films of Titanium and Titanium nitride where the transition temperature can be tailored by simply changing thickness and ratio of the employed metal layers.

In 2006 he become the head of the “MEMS” group of the MIS (MicroSystems) Division at ITC-irst. Since the beginning of 2008 he was responsible for the MEMSRaD Research Unit of FBK, which in 2010 became the MEMS Research Unit and in 2014 has been incorporated in the Microsystems group led by Ing. L. Lorenzelli.

Presently, B. Margesin’s scientific interest is related to the development of passive RF components on silicon (switches), cavity microwave filters, cryogenic bolometers, Josephson junctions and physical sensors for consumer and industrial applications.

He has lead 3 ESA projects and was involved in a number of European and industrial projects. Actually he is involved in one ESA project on MEMS cavity high frequency filters and in different industrial projects.

He is author and co-author of more than 330 scientific papers on national and international journals and co-author of invited talks of national and international conferences. He is also co-inventor of a patent in the field of biomedical devices for the measurement of the metabolic activity of living cells.